

Please replace paragraph [0006] on page 2 with the following:

C2 [0006] U.S. Patent No. 6,277,318 entitled "Method for Fabrication of Patterned Carbon Nanotube Films", the disclosure of which is incorporated herein by reference, in its entirety, discloses a method of fabricating adherent, patterned carbon nanotube films onto a substrate.

Please replace paragraph [0007] on page 2 with the following:

C3 [0007] U.S. Patent No. 6,334,939 entitled "Nanostructure-Based High Energy Material and Method", the disclosure of which is incorporated herein by reference, in its entirety, discloses a nanostructure material having an intercalated alkali metal. Such materials are described as being useful in certain battery applications.

Please replace paragraph [0023] on page 5 with the following:

C4 [0023] According to a further aspect, the present invention is directed to an improved circuit, optionally comprising at least one of an interface device box and central office switching gear, and comprising a gas discharge device of the present invention.

Please replace paragraph [0036] on page 7 with the following:

C5 [0036] According to the present invention, an electrode is formed, at least in part, by a nanostructure-containing material. Nanostructure-containing materials are characterized by having basic building blocks that are nanometer-sized in at least one direction. Examples of such basic building blocks include nanoparticles, cage-like fullerene

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molecules, carbon nanotubes, and silicon nanorods. These basic building blocks can be formed, for example, of carbon, silicon, germanium, aluminum, silicon oxide, germanium oxide, silicon carbide, boron, boron nitride, and boron carbide, etc., or a mixture of such materials.

Please replace paragraph [0037] on page 7 with the following:

C6
[0037] According to a preferred embodiment of the present invention, the basic building block of the nanostructure-containing material is carbon nanotubes, preferably single-walled carbon nanotubes. These single-walled carbon nanotubes can be formed by what are now considered "conventional" techniques, such as laser ablation, arc-discharge, and chemical vapor deposition techniques. More specific details of such materials and their fabrication can be gleaned, for example, from U.S. Patent No. 6,334,939 and U.S. Patent No. _____ (Serial No. 09/259,307).

IN THE CLAIMS:

Please replace claims 1, 4, 15, 39 and 42 as follows:

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1. (Amended) An electrode comprising a first electrode material, an adhesion-promoting layer disposed on at least one surface of the first electrode material, and a layer of pre-formed nanostructure-containing material comprising at least one of nanotubes and nanorods disposed on at least a portion of the adhesion-promoting layer.
